

In the Office Action dated July 3, 2001, paper number 9, the Examiner states:

It is noted that the dictionary definition of "at" is "a function word used to indicate presence or occurrence in, on or near". Giving the word its broadest reasonable interpretation, the phrase "located at" means broadly "located near". The dictionary definition of the word "near" is "not far from". It is inherent or at least obvious from the schematic of Shinriki that the first gas inlet manifold valve **is not far from** the semiconductor unit. (Office Action, page 2, emphasis added.)

Accordingly, the Examiner asserts that "It is inherent or at least obvious from the schematic of Shinriki that the first gas inlet manifold valve **is not far from** the semiconductor unit." However, Claim 10, as amended, recites a system comprising:

- a semiconductor processing reactor;
- a gas manifold;
- a first process gas source located at a first location;
- a first regulator coupled to said first process gas source, said first regulator located at said first location;
- a first gas manifold inlet valve coupled between said first regulator and said gas manifold, wherein said gas manifold and **said first gas manifold inlet valve are located as close as physically possible to said semiconductor processing reactor** and at a second location separate and removed from said first location;
- a second process gas source located at said first location;
- a second regulator coupled to said second process gas source, said second regulator located at said first location; and
- a second gas manifold inlet valve coupled between said second regulator and said gas manifold, **said second gas manifold inlet valve located as close as physically possible to said semiconductor processing reactor** and at said second location. (Emphasis added.)

Applicant respectfully submits that the Examiner has failed to call out where Shinriki et al. teaches or suggests a

system as recited in amended Claim 10. Accordingly, Claim 10 is allowable over Shinriki et al. Claim 11, which depends from Claim 10, is allowable for at least the same reasons as Claim 10.

Amended Claim 35 recites a gas flow control system for a semiconductor processing unit comprising:

- a first process gas source located at a first location;
- a first mass flow controller located at said first location and coupled to said first process gas source;
- a support structure located at said semiconductor processing unit;**
- a gas manifold attached to said support structure;**
- a first gas manifold inlet valve attached to said support structure** and coupled between said gas manifold and said first mass flow controller;
- a second process gas source located at said first location;
- a second mass flow controller located at said first location and coupled to said second process gas source; and
- a second gas manifold inlet valve attached to said support structure** and coupled between said gas manifold and said second mass flow controller,

wherein said gas manifold, said first gas manifold inlet valve and said second gas manifold inlet valve are located at a second location separate and removed from said first location, a first process gas from said first process gas source and a second process gas from said second process gas source mixing in said gas manifold. (Emphasis added.)

Applicant respectfully submits that the Examiner has failed to call out where Shinriki et al. teaches or suggests a gas flow control system as recited in amended Claim 35. Accordingly, Claim 35 is allowable over Shinriki et al.

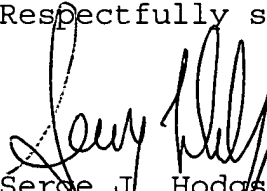
For the above reasons, Applicant respectfully requests reconsideration and withdrawal of this rejection.

CONCLUSION

Claims 1-11, 22, 25-28 and 35-37 are pending in the application. For the foregoing reasons, Applicant respectfully

requests allowance of all pending claims. If the Examiner has any questions relating to the above, the Examiner is respectfully requested to telephone the undersigned Attorney for Applicant(s).

Respectfully submitted,



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VIA HAND DELIVERY